



Session Title:	[WA2] Advanced Atomic Scale Thin Films VII
Session Date:	November 22 (Wed.), 2023
Session Time:	10:20-12:00
Session Room:	Room A (Capri Room, 2F)
Session Chair:	Prof. Sean Barry (Carleton Univ., Canada)

[WA2-1] [Invited]

10:20-10:50

Advanced Process Technologies for Future Logic Devices

Honggun Kim, Chungil Hyun, Hyungi Kim, Sangwoo Lee, Youngseop Rah, Changgu Jung, Kyoungho Jang, Changwon Choi, Seongtae Oh, Seungwoo Choi, Youngwoo Park, and Jaihyung Won (Tokyo Electron Korea Ltd., Korea)

[WA2-2] [Invited]

10:50-11:20

Advanced Deposition Materials for Atomic Layer Deposition and Beyond

Changbong Yeon, Jaesun Jung, Seung Hyun Lee, Kok Chew Tan, Tai-su Park, and Young-Soo Park (Soulbrain, Korea)

[WA2-3] [Invited]

11:20-11:40

Memtransistor Devices based on 2D Layered Semiconductor for Energy-Efficient Neuromorphic Computing

Byungjin Cho (Chungbuk Nat'l Univ., Korea)

[WA2-4] [Invited]

11:40-12:00

SMART Metallization for Reliable and Power-Efficient Hetero-Integrated Systems

Hanwool Yeon (GIST, Korea)